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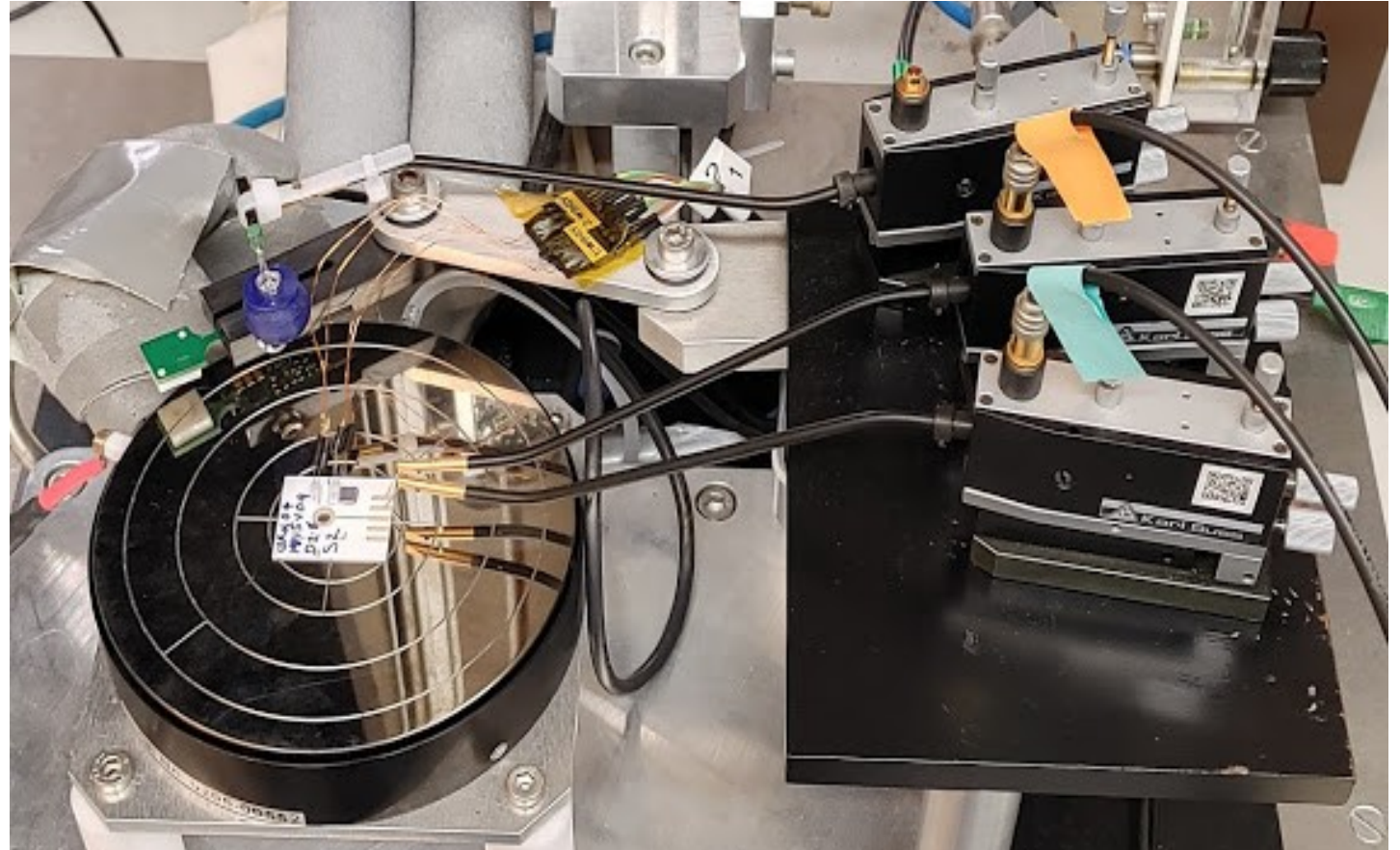
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Carmen Villalba - SiPM Self-Heating



Outline

- 👉 Introduction
- 👉 Aim of the study
- 👉 Method developed
- 👉 Setup used
- 👉 First results
- 👉 Cross-check
- 👉 Summary
- 👉 Next steps



Introduction

- The most critical effect of radiation damage is the increase in dark current (I_{dark}) which is proportional to the fluence:
 - Increase in I_{dark} leads to a significant power dissipation;
 - If the power dissipated is not properly cooled, it heats the SiPM, whose performance parameters depend on temperature:

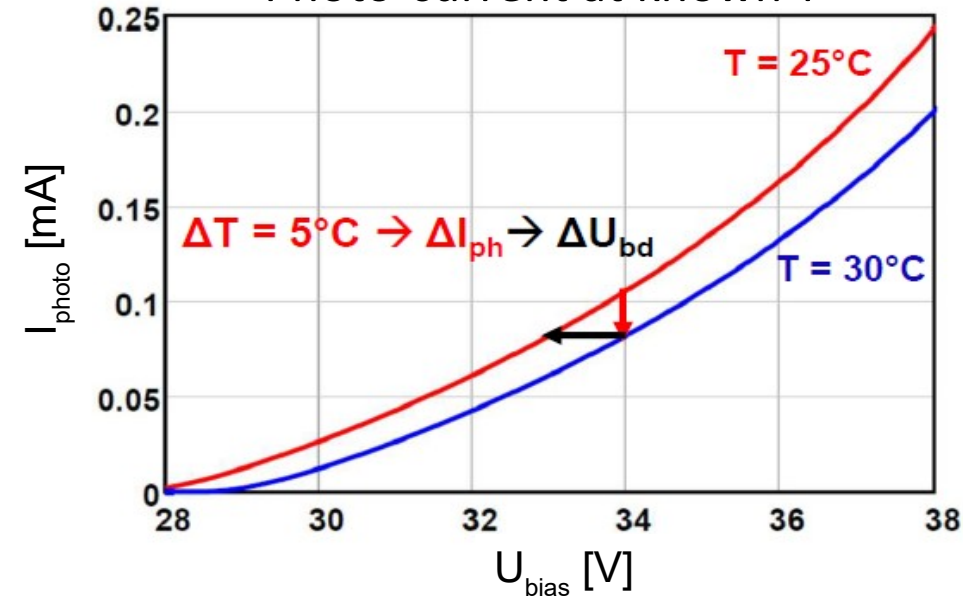
- Photo-current ($I_{\text{photo}} = I_{\text{SiPM}} - I_{\text{dark}}$) at constant bias voltage, U_{bias} , and constant photon rate, decreases with temperature:

$$I_{\text{photo}} \propto \text{PDE}(T) \cdot \text{Gain}(T)$$

- Explained, among other effects, by the temperature dependence of breakdown voltage, U_{bd} :

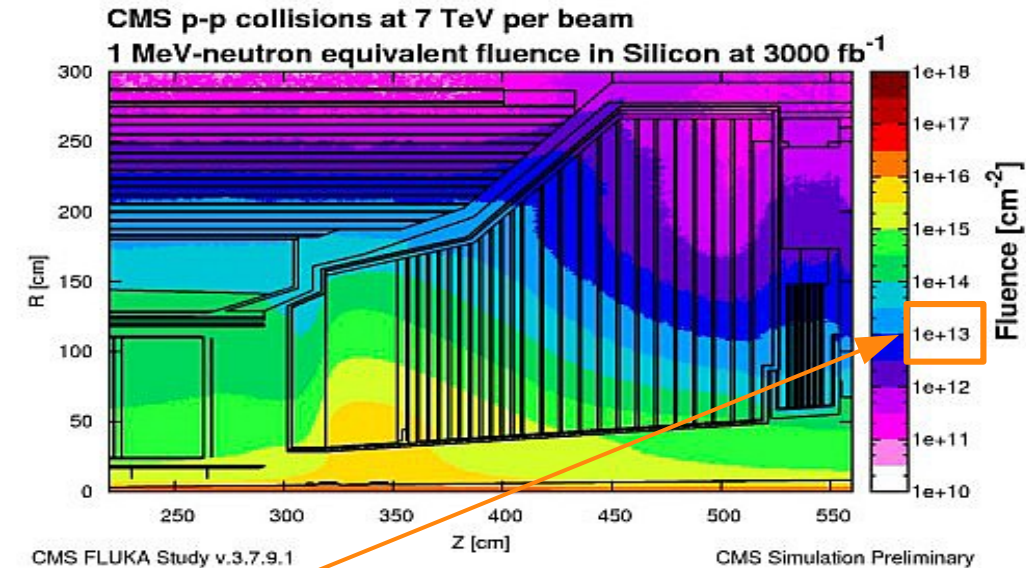
$$\text{Gain} \propto \frac{1}{q_0} C_{\text{pix}} (U_{\text{bias}} - U_{\text{bd}}(T))$$

Calibration $I_{\text{ph}}(U, T)$:
Photo-current at known T



Aim

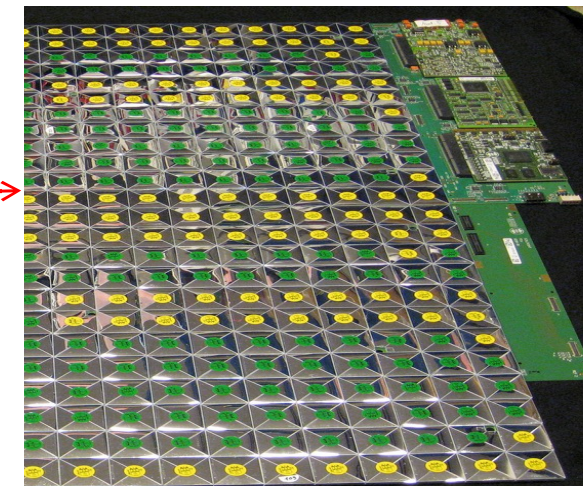
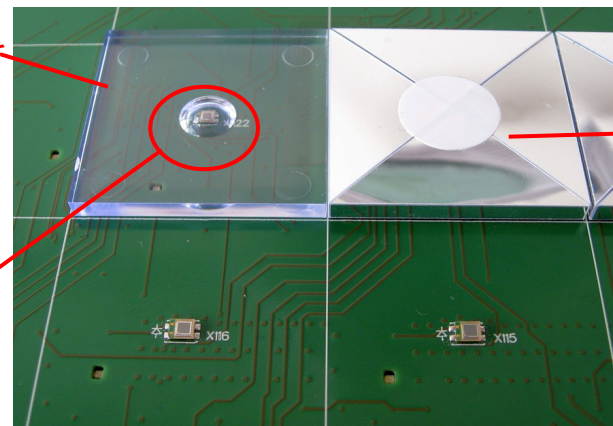
- Develop a method to determine SiPM temperature increase induced by power dissipated (self-heating) $\Delta T_{SiPM}(P)$ with $P = I_{SiPM} \cdot U_{bias}$
- Relevant for applications of SiPMs in:
 - ♦ High background light experiments \rightarrow High I_{photo}
 - Light Detection and Ranging (LIDAR), astrophysics
 - ♦ High radiation environment \rightarrow High I_{dark}
 - Satellite experiments, HL-LHC (~ 1 mA, $T = -30$ °C, $\phi_{eq} \sim 10^{13}$ cm⁻²)



Replacement of the CMS calorimeter endcaps with the High Granularity Calorimeter (HGCal)

Scintillator Tile

SiPM



Aim

- I_{dark} increases with fluence, in particular for this study we want to **emulate the power dissipated by I_{dark} in an irradiated SiPM**

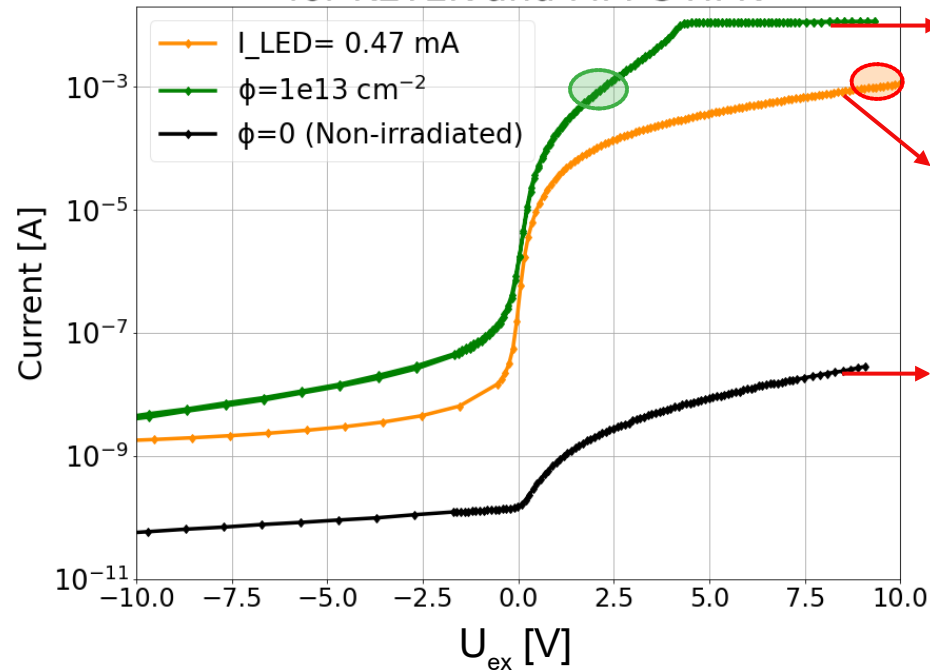
→ Operate a non-irradiated SiPM, under LED illumination, to produce the same power as expected for an irradiated SiPM

- Power dissipated (P):

- **$P \sim 50 \text{ mW}$ induced by I_{dark} (Irrad. at $\phi = 1\text{e}13 \text{ cm}^{-2}$ at $U_{\text{ex}} = 2 \text{ V}$, $U_{\text{bd}} = 36.7 \text{ V}$ @ $-30 \text{ }^\circ\text{C}$)**

- **$P \sim 50 \text{ mW}$ induced by high I_{LED} (Non-irrad. $I_{\text{LED}} \sim 0.5 \text{ mA}$ at $U_{\text{ex}} = 10 \text{ V}$, $U_{\text{bd}} = 27.5 \text{ V}$ @ $25 \text{ }^\circ\text{C}$)**

SiPM current as a function of over voltage for KETEK and MPPC HPK



Irradiated MPPC HPK SiPM
($I_{\text{LED}} = 0 \text{ mA}$, $-30 \text{ }^\circ\text{C}$)

Non-irradiated KETEK SiPM
($I_{\text{LED}} = 0.47 \text{ mA}$, $25 \text{ }^\circ\text{C}$)

Non-irradiated MPPC HPK SiPM
($I_{\text{LED}} = 0 \text{ mA}$, $-30 \text{ }^\circ\text{C}$)

$$U_{\text{ex}} = U_{\text{bias}} - U_{\text{bd}}$$

Method

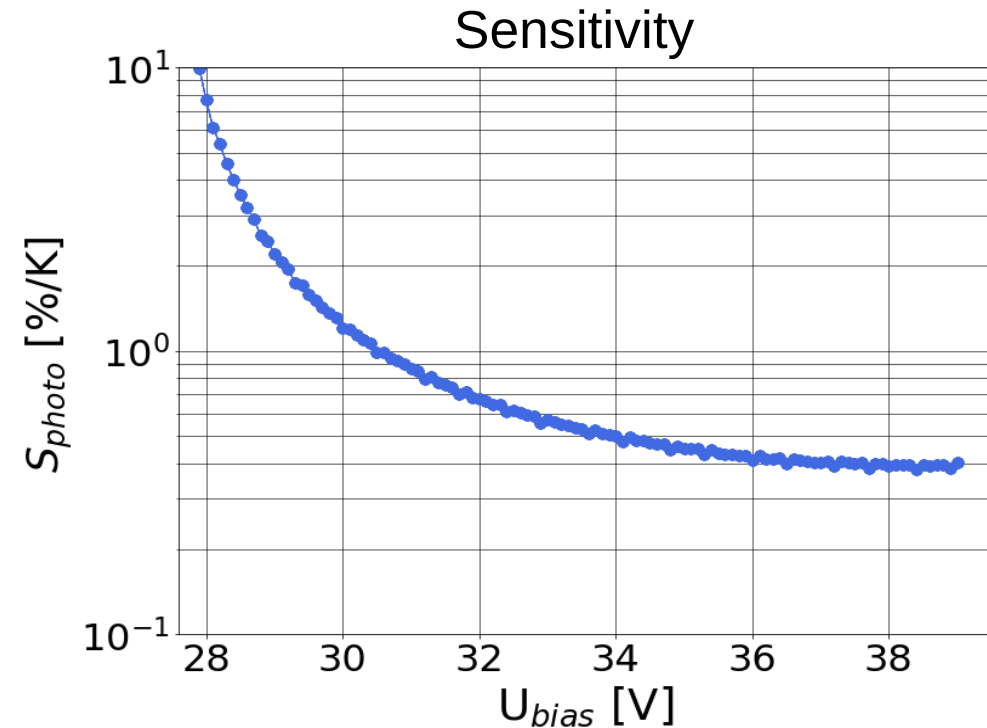
- Express the T dependence of photo-current as: $\frac{dI_{photo}}{dT} = \frac{dI_{photo}}{dU} \cdot \frac{dU_{bd}}{dT}$

- A relative change in photo-current is related to a change in T by the **sensitivity**

$$\frac{\Delta I_{photo}}{I_{photo}} = S_{photo} \cdot \Delta T$$

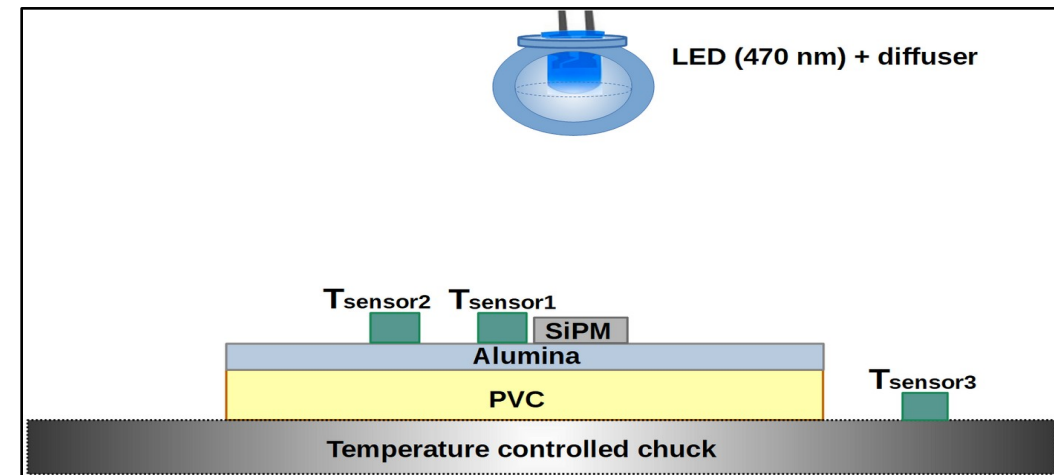
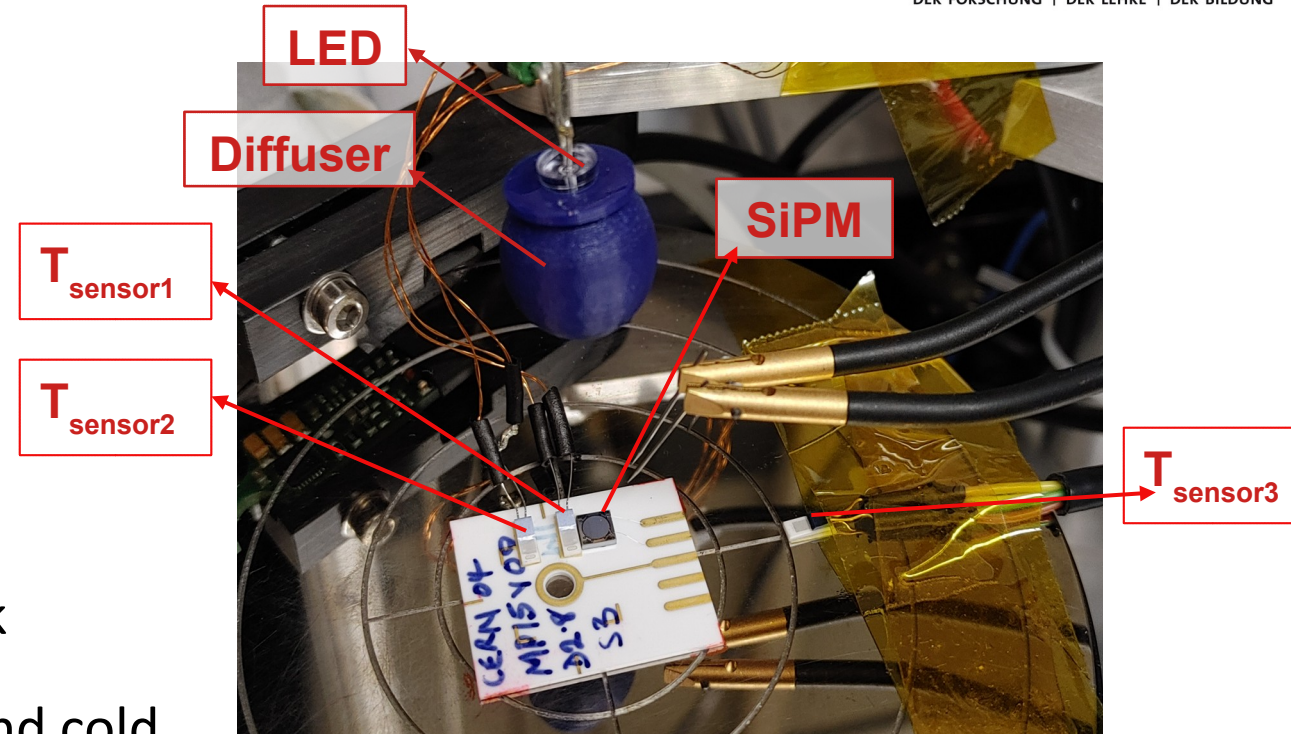
Sensitivity: $S_{photo}(U_{bias}, T_{chuck}) = \frac{1}{I_{photo}} \cdot \frac{dI_{photo}}{dU} \cdot \frac{dU_{bd}}{dT} \left[\frac{\%}{K} \right]$

- Typical sensitivity: (0.4 – 1) %/K
- Precision data required:
LED-stability, I-measurement, U-setting.
- Extract T_{SiPM} from I_{SiPM} in a cycle at constant U_{bias} and changing light intensity.
- Lucchini et al propose a method with constant illumination, and T_{SiPM} is derived from the changes in I_{SiPM} when the U is switched on, or thermal conditions change by switching on a fan.
[doi:10.1016/j.nima.2020.164300]



Setup

- SiPM KETEK *non-irradiated* (MP15V09 D2.8)
 - $d_{Si} = 700 \mu\text{m}$
 - $U_{bd} = 27.5 \text{ V @} 25^\circ\text{C}$, $C_{pix} = 18 \text{ fF}$, $\tau = 14 \text{ ns}$
 - Pixel size = $15 \mu\text{m}$, 27000 pixels
- SiPM glued on alumina (Al_2O_3) substrate:
 - $d_{\text{Al}_2\text{O}_3} = 600 \mu\text{m}$
- Cooling system: temperature-controlled chuck
- PVC (1.2 and 3.1 mm) between the alumina and cold chuck to emulate degraded thermal contact.
- Three T sensors (PT-100): at 3.1 mm (T_{sensor1}) and 7.6 mm (T_{sensor2}) from the SiPM center, T_{sensor3} on the chuck.
- Illumination: LED (470 nm)

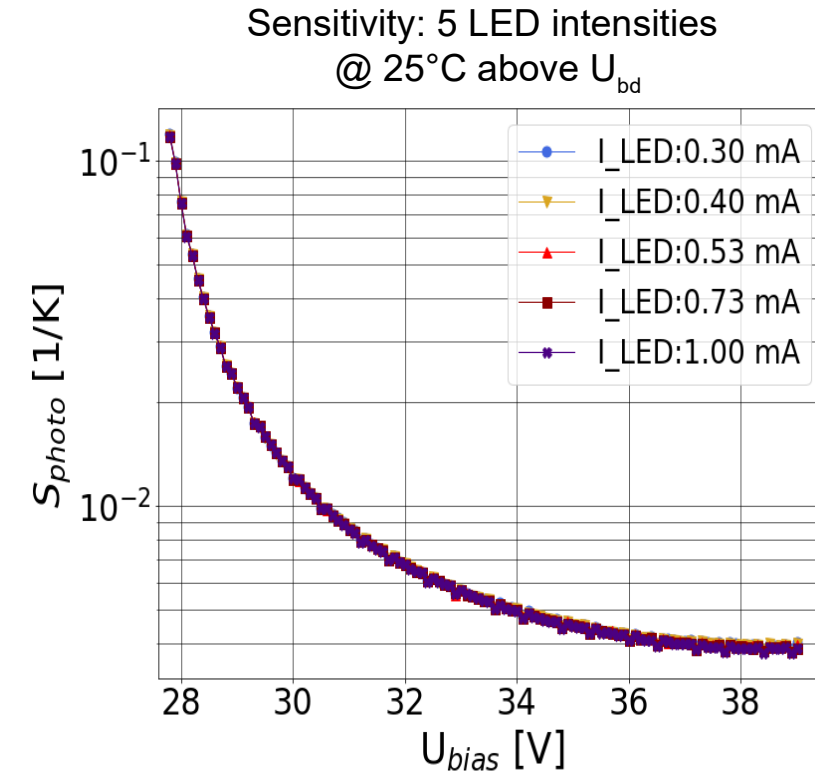
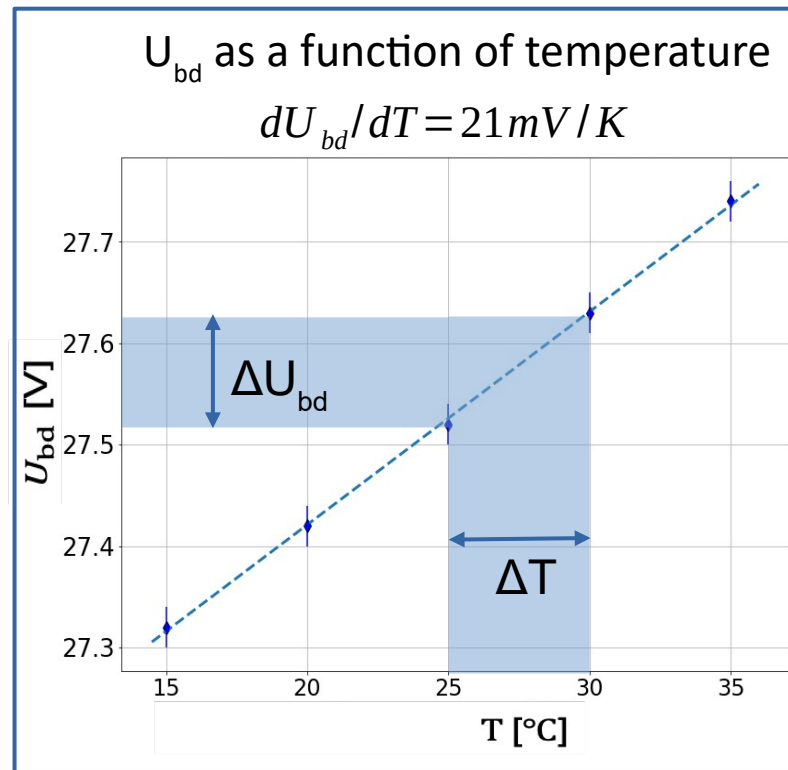
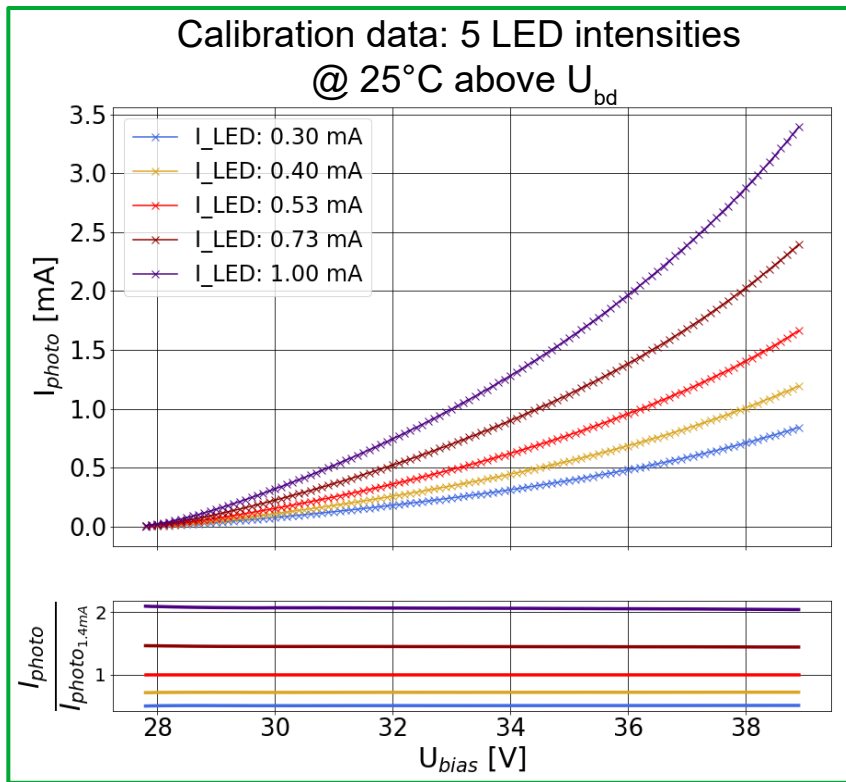


Sensitivity calibration

Sensitivity: $S_{photo}(U_{bias}, T_{chuck}) = \frac{1}{I_{photo}} \cdot \frac{dI_{photo}}{dU} \cdot \frac{dU_{bd}}{dT} \left[\frac{\%}{K} \right]$

- Calibration data is measured at known and stable T_{chuck} , avoiding saturation due to occupancy (~1%):

- Calibration data at several LED currents leads to the same sensitivity curve.
- Measure in the T range of relevance



Results for degraded thermal contact (3.1 mm PVC)

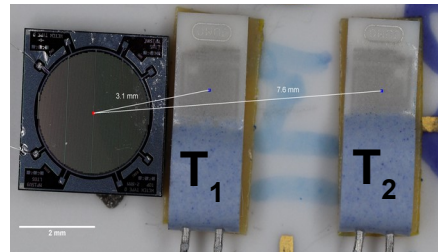
- $U_{\text{bias}} = 38 \text{ V}$, $I_{\text{LED}} = 0.47 \text{ mA}$, $P = 58 \text{ mW}$:

$$\Delta T_{\text{SiPM}} = \frac{\Delta I_{\text{photo}}}{S_{\text{photo}} \cdot I_{\text{photo}}}$$

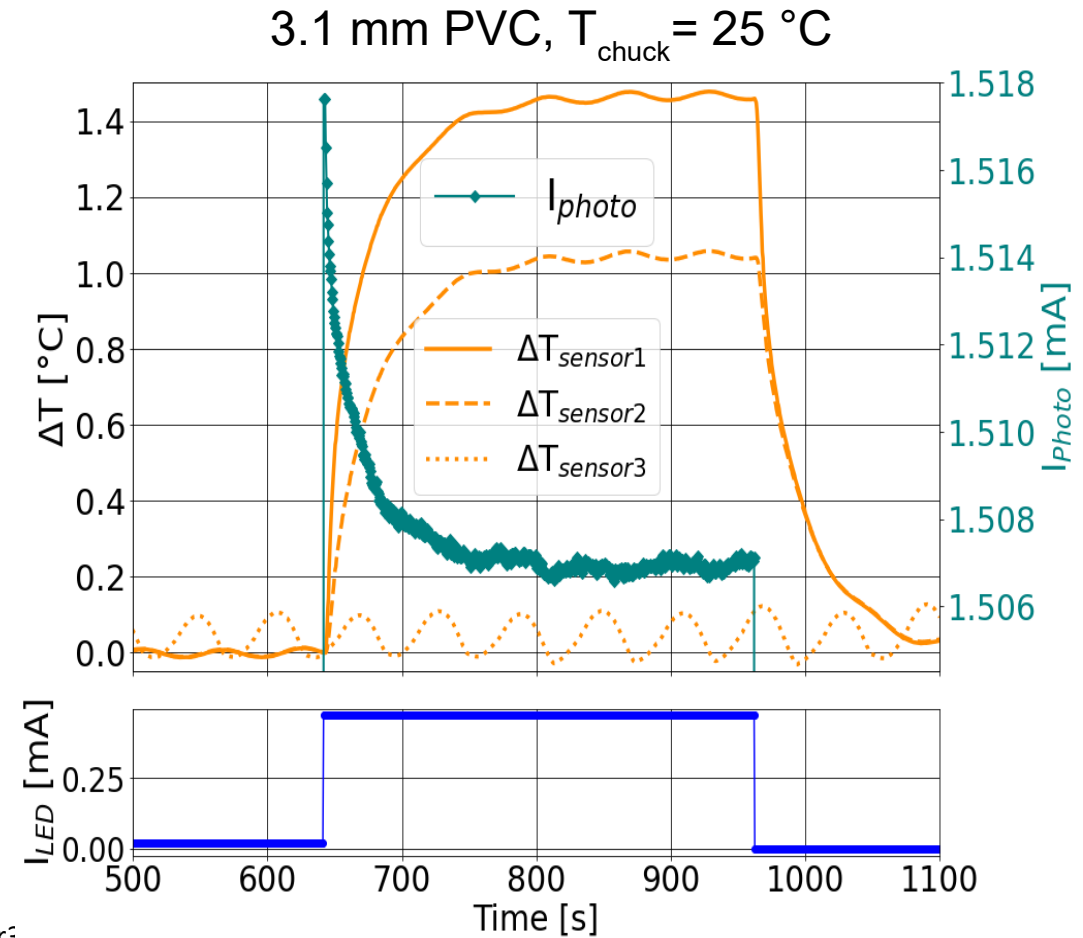
- From sensitivity calibration for $U_{\text{bias}} = 38 \text{ V} \rightarrow S_{\text{photo}} = 0.39 \%$
- Observed: $\frac{\Delta I_{\text{photo}}}{I_{\text{photo}}} = 0.73 \%$
- Calculated: $\Delta T_{\text{SiPM}} = 1.87 \text{ K}$, reached in $\sim 60 \text{ s}$, $\Delta U_{\text{bd}} = 39 \text{ mV}$

- As expected from heat flow:

$$\Delta T_{\text{sensor1}} > \Delta T_{\text{sensor2}} \gg \Delta T_{\text{sensor3}}$$



- Due to the increased thermal resistance \rightarrow change of the amplitude and phase of $\Delta T_{\text{sensor1}}$ and $\Delta T_{\text{sensor2}}$ relative to $\Delta T_{\text{sensor3}}$

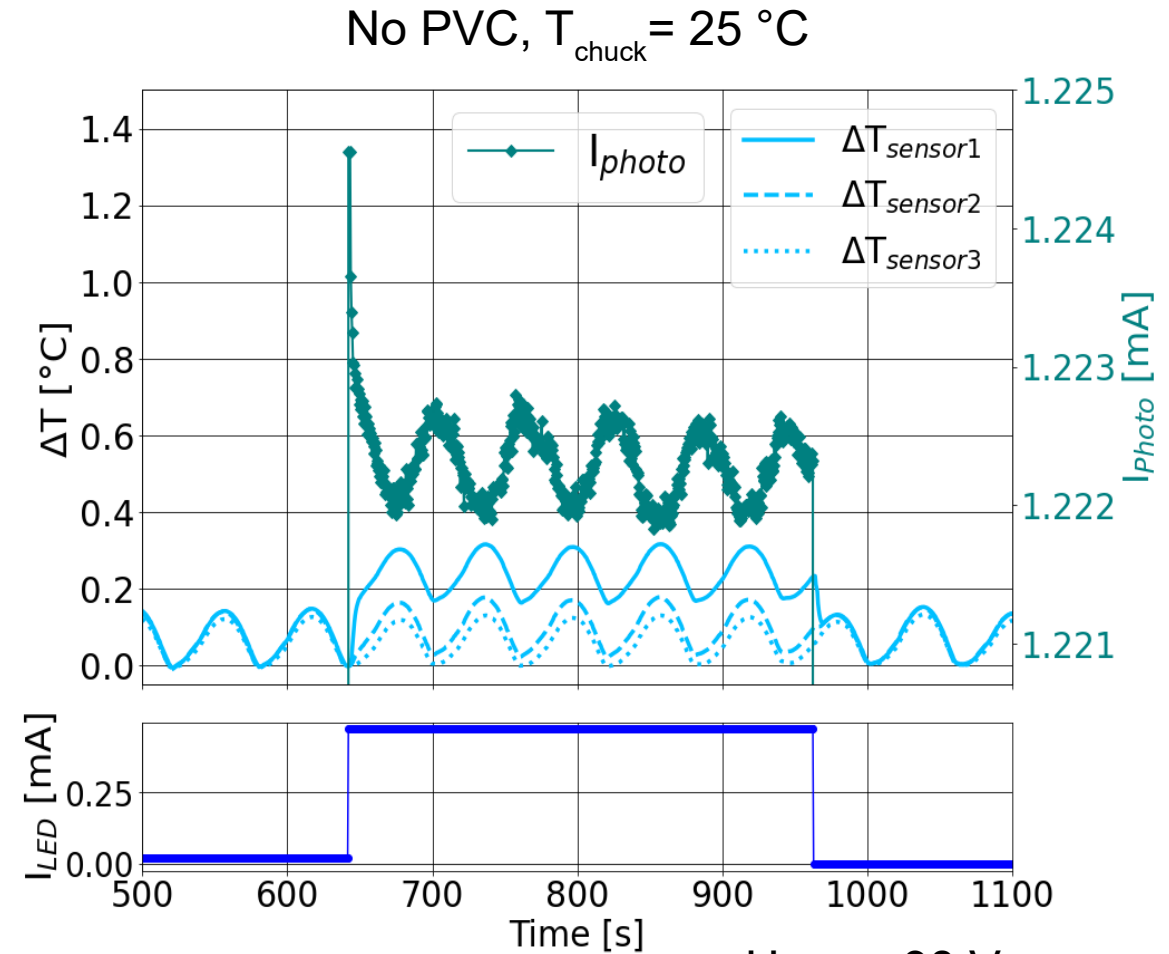


T oscillations due to feedback loop of the temperature-controlled chuck

Results for good thermal contact (no PVC)

- $\Delta T_{\text{SiPM}} \sim 0.5 \text{ K}$, for $P = 47 \text{ mW}$ reached in $\sim 2 \text{ s}$.
 $\Delta U_{\text{bd}} = 12 \text{ mV}$
- T oscillations due to feedback loop of the temperature-controlled chuck:
 - ◆ T_{sensors} with the same amplitude and phase
 - ◆ T_{SiPM} anti-correlated with I_{photo} , an increase in T_{SiPM} causes a decrease of I_{photo}

→ Phase shift of 180° between T_{sensors} and I_{photo} demonstrates good thermal contact between chuck and SiPM multiplication region.

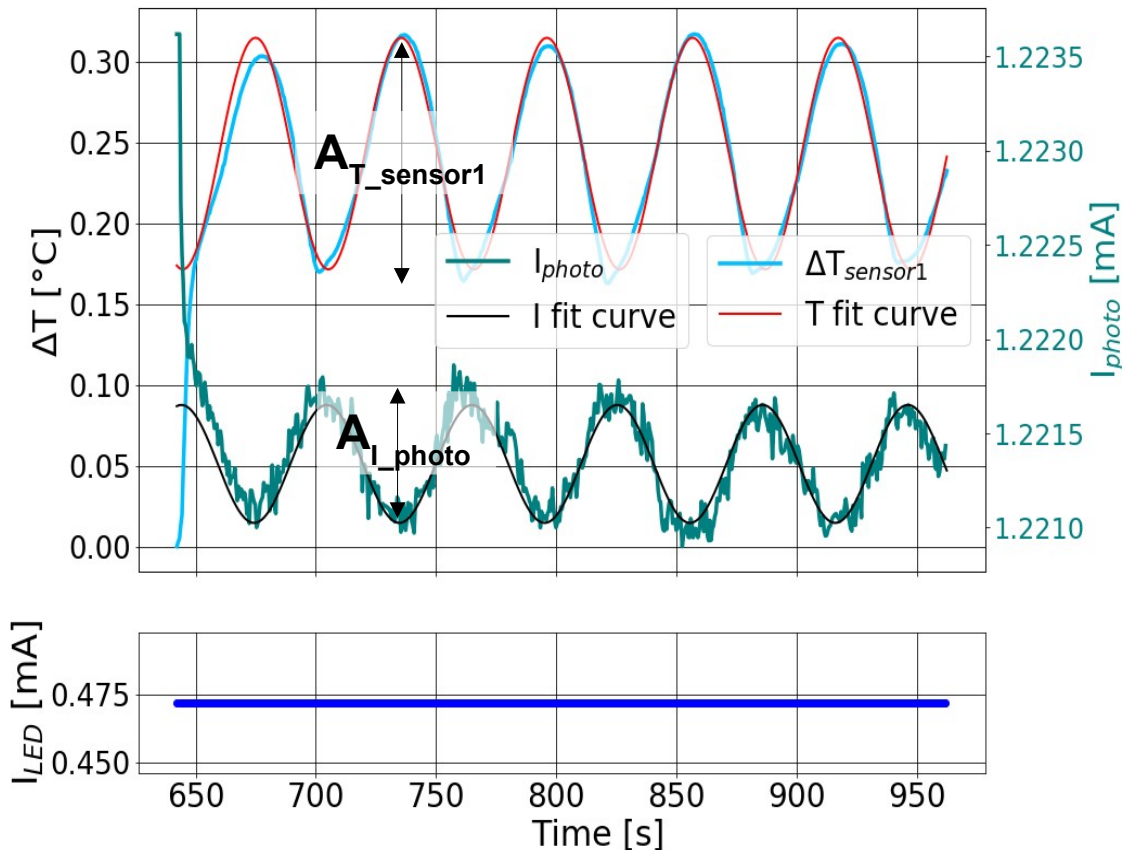


$U_{\text{meas}} = 38 \text{ V}$,
 $I_{\text{LED}} = 0.47 \text{ mA}$.

Cross-check

- T-oscillations to check ΔT_{SiPM} determination:

No PVC: $T_{sensor1}$ and I_{photo} $T_{chuck} = 25\text{ }^\circ\text{C}$



- No PVC and $I_{photo} = 1.22\text{ mA}$:

- Fitting data to obtain amplitude of both T and I_{photo}

$$\alpha = \frac{A_{T_{sensor1}}}{A_{I_{photo}}} = 0.23 \left[\frac{K}{\mu A} \right]$$

- Current normalized to the maximum value of the data without PVC

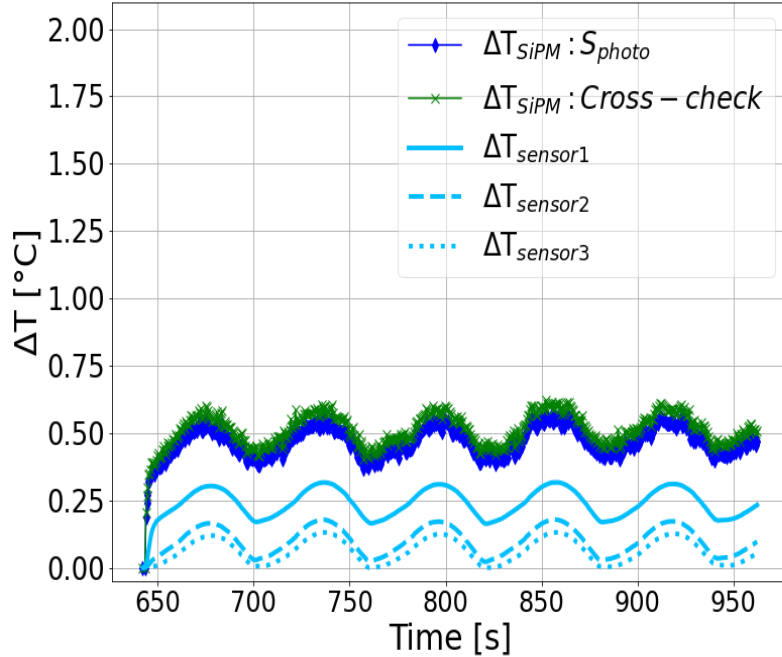
$$\Delta T_{SiPM} = \alpha \cdot \Delta I_{photo}$$

- For good thermal contact, $P = 47\text{ mW}$

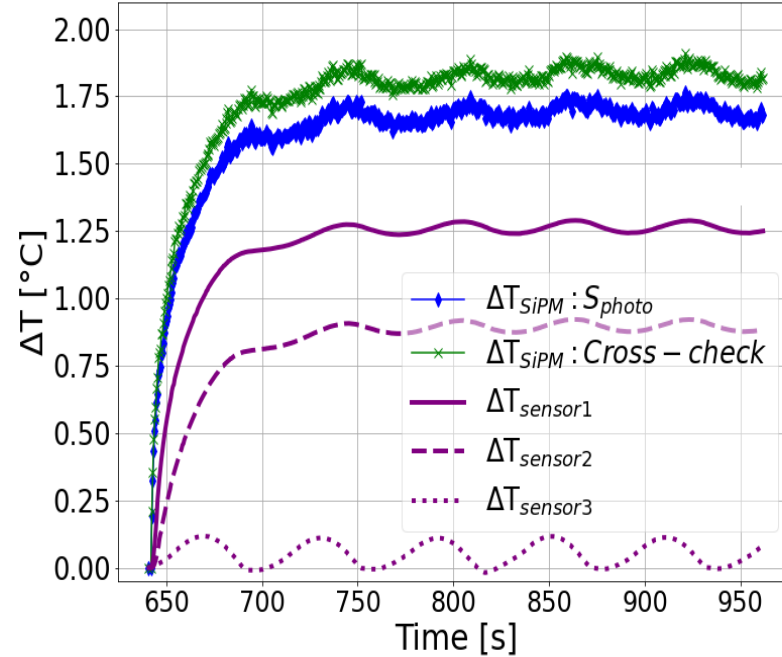
$$\rightarrow \Delta T_{SiPM} = 0.62\text{ K}$$

Summary of preliminary results

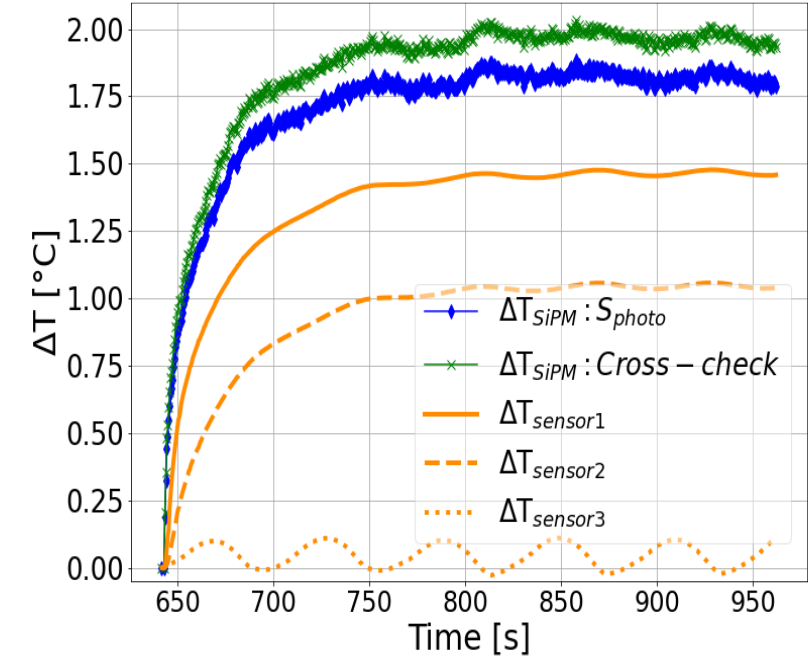
No PVC



1.2 mm PVC



3.1 mm PVC



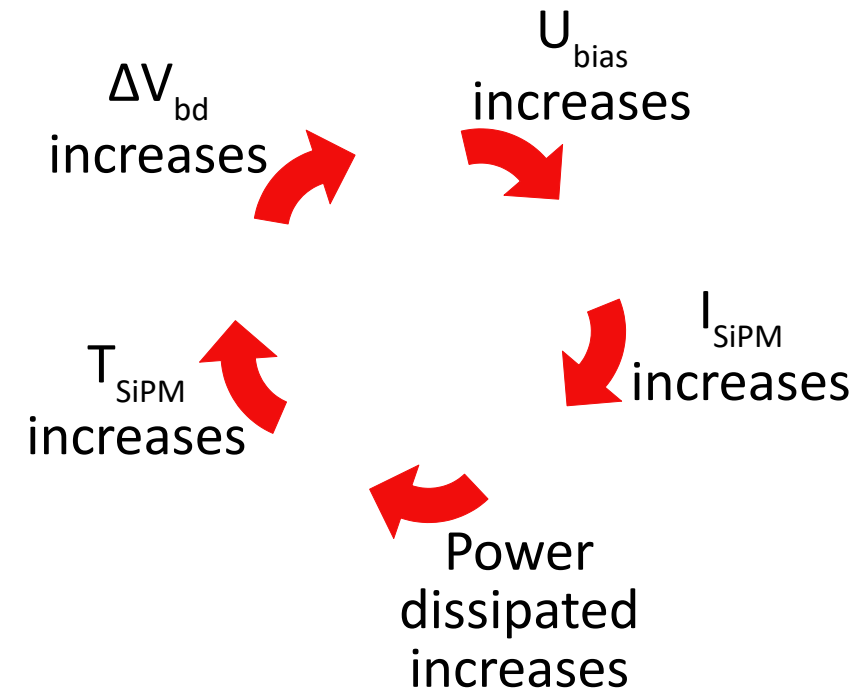
- Sensitivity method and cross-check agree: same ΔT_{SiPM} from the measured current within 10%

$U_{bias} = 38 \text{ V}$
 $T_{chuck} = 25 \text{ }^\circ\text{C}$

	P [mW]	ΔU_{bd} [mV]	ΔT_{SiPM} [K]	Cross-check ΔT_{SiPM} [K]	Rel. difference	
~SiPM on top of cooling system → no PVC	46.55	12	0.56	0.62	10.3%	
~ SiPM mounted on PCB {	PVC (1.2 mm)	50.81	37	1.74	1.91	9.5%
	PVC (3.1 mm)	57.68	39	1.87	2.03	8.6%

Implications:

- If the shift of 40 mV is not compensated, operating $\sim U_{ex} = 2\text{ V} \rightarrow$ reduction of gain by 2 % + reduction of PDE by 2 %
- Reduction of signal about 4 %
- Increasing U_{bias} is a possible solution **but**:




 It is a loop! Cannot be fully compensated.

Next Steps:

- Extend the method to determine T_{SiPM} using I_{dark} during the cool down phase after switching off the LED
- Study the self-heating as function of dissipated power
- Investigate the self-heating of irradiated SiPMs
- Compare the measurements to predictions from thermal simulations

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- Extend the method to determine T_{SiPM} using I_{dark} during the cool down phase after switching off the LED
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*Many thanks for
your attention!*

Backup slides

Heat in the multiplication region (single Geiger discharge)

Data for MP15V09 D2.8:

- $C_{pix} = 18 \text{ fF}$
- $V_{bias} = 38 \text{ V}$
- $V_{bd} = 27.5 \text{ V}$
- $r_{dis} = 5 \text{ }\mu\text{m}$
- $d = 2 \text{ }\mu\text{m}$
- # Pixels = 27367

⇒ Heat of 1 discharge $\Delta T = 24 \text{ mK}$

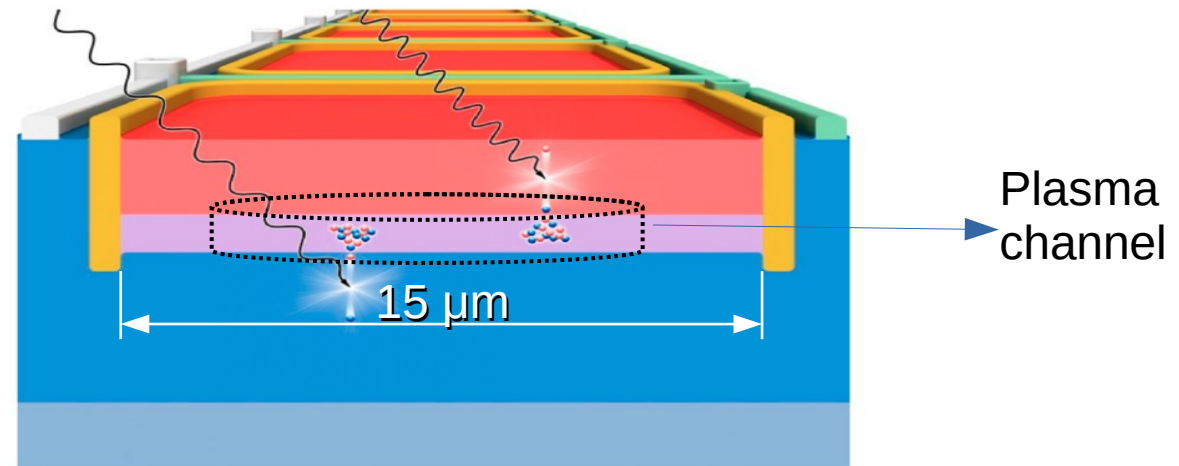
⇒ Heat for 0.3% of the pixels $\Delta T \sim 2 \text{ K}$

- Geiger discharge through a plasma channel;
- Temperature change:

$$\Delta T_{dis} = W_d / (c_{Si} \cdot M_{Si}) \equiv \frac{1}{2} \frac{C_d \cdot (V_{bias}^2 - V_{off}^2)}{r_{dis}^2 \cdot \pi \cdot d \cdot \rho_{Si} \cdot c_{Si}}$$

Thermal parameters: Different sources give quite different values

	k [W/(cm K)]	c [J/(g K)]	D [cm ² /s]	ρ [g/cm ³]
Si	1.5	0.7	0.92	2.328



Implementation of Analysis method for constant U_{meas}

1) The I_{SiPM} is normalised to $I_{cal}(U_{cal}, T_{chuck})$: $I_{cal}^{norm} = \frac{I_{cal}(U_{cal}, T_{chuck})}{I_{cal}(U_{bias}, T_{chuck})}$.

2) A cubic spline fit is used to obtain U : $U_{spl}(I_{cal}^{norm})$

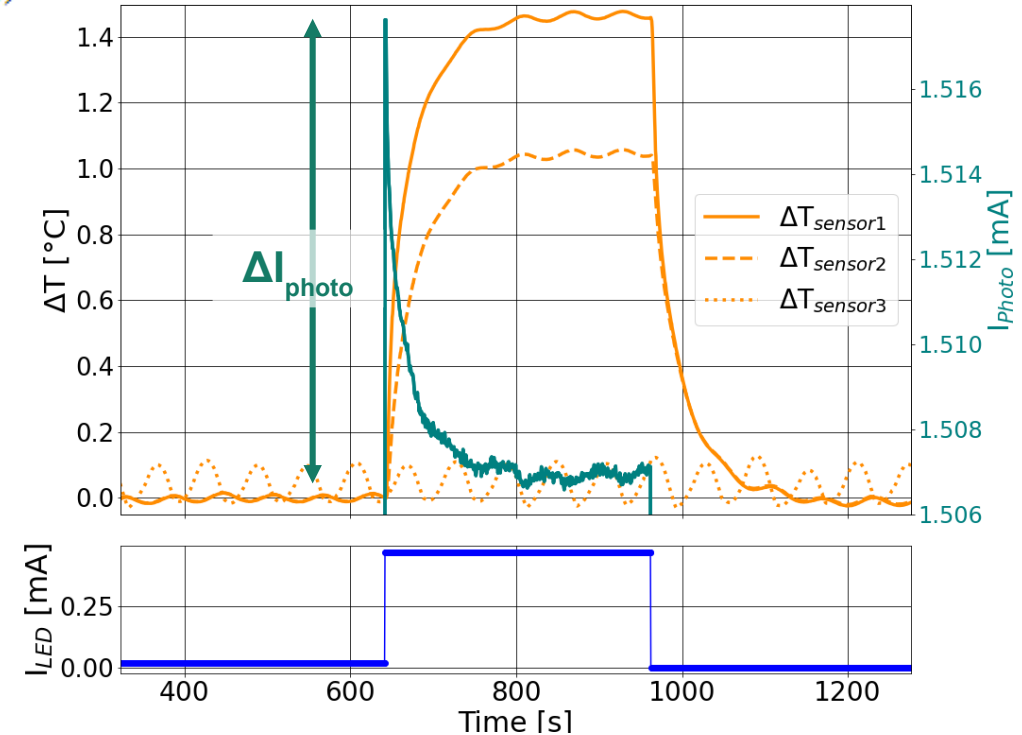
3) The measured $I_{SiPM(t)}$ is normalised:

$$I_{SiPM}^{norm}(t) = I_{SiPM}(t) / I_{SiPM}(t+), \text{ where } t+ \text{ is the time of the 1}^{st} \text{ measurement after switching } I_{LED}$$

4) The change in current is converted into a voltage change using $\Delta U(t) = U_{bias} - U_{spl}(I_{SiPM}^{norm}(t))$

5) And the increase in temperature is determined using: $\Delta T_{SiPM} = \frac{\Delta U(t)}{dU_{bd}/dT}$, $dU_{bd}/dT = 21 \text{ mV/K}$

3.1 mm PVC, $T_{chuck} = 25 \text{ }^\circ\text{C}$

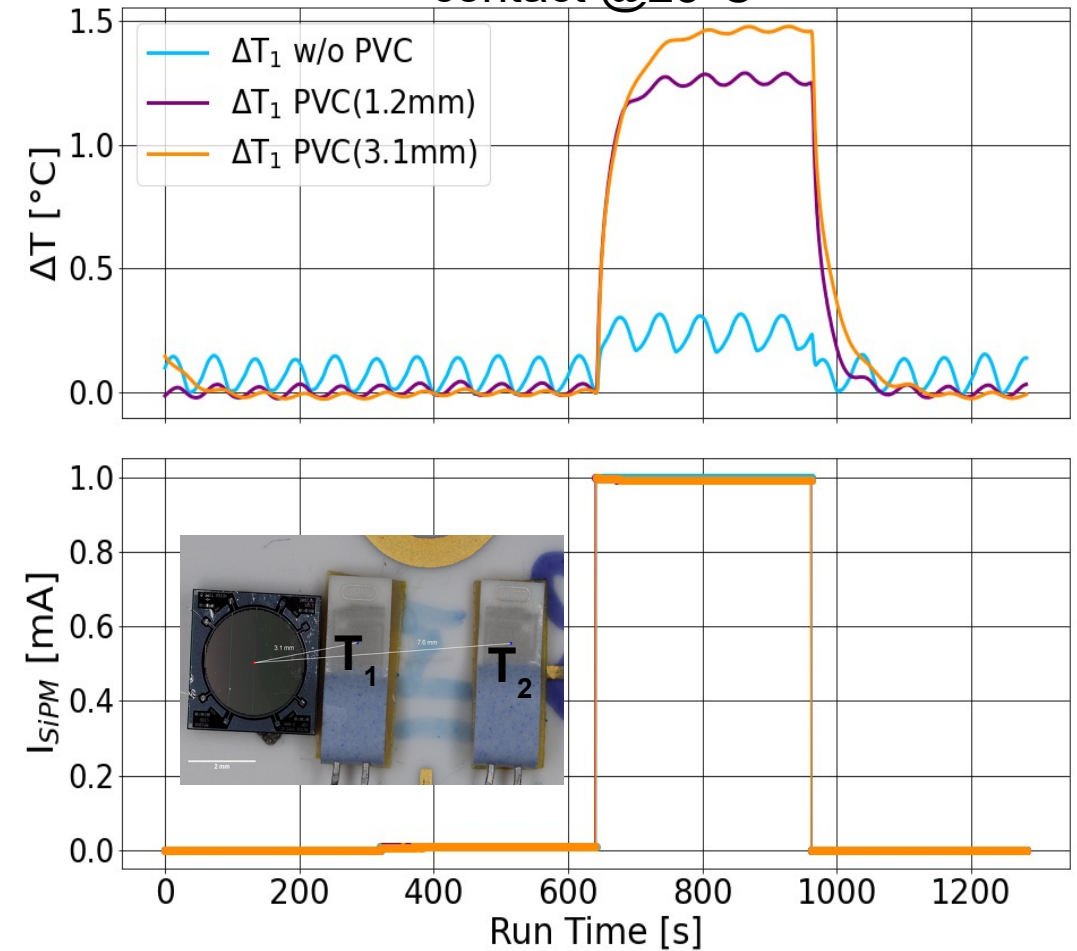


$$\frac{\Delta I_{photo}}{I_{photo}} = 0.73\% \quad \begin{matrix} U_{meas} = 38 \text{ V,} \\ I_{LED} = 0.47 \text{ mA,} \\ P = 58 \text{ mW.} \end{matrix}$$

Measurements for self-heating (I_{LED} -steps)

- I_{SiPM} and T sensors recorded with step 0.5 s
- Cycle with fixed applied Voltage:
 - 320 s with LED off ($I_{dark}, I_{LED} = 0$ mA)
 - 320 s with LED on ($I_{dark} + I_{photo-low}, I_{LED} = 0.02$ mA)
 - 320 s with LED on ($I_{dark} + I_{photo-high}, I_{LED} = 0.47$ mA)
 - 320 s with LED off ($I_{dark}, I_{LED} = 0$ mA)
- LED intensity tuned to have $I_{SiPM} \sim 1$ mA
- Measurements with efficient thermal contact: without PVC
- To degrade the thermal contact: PVC layers of thickness 1.2mm and 3.1 mm

$T_{sensor1}$ and I_{SiPM} for the different thermal contact @25°C



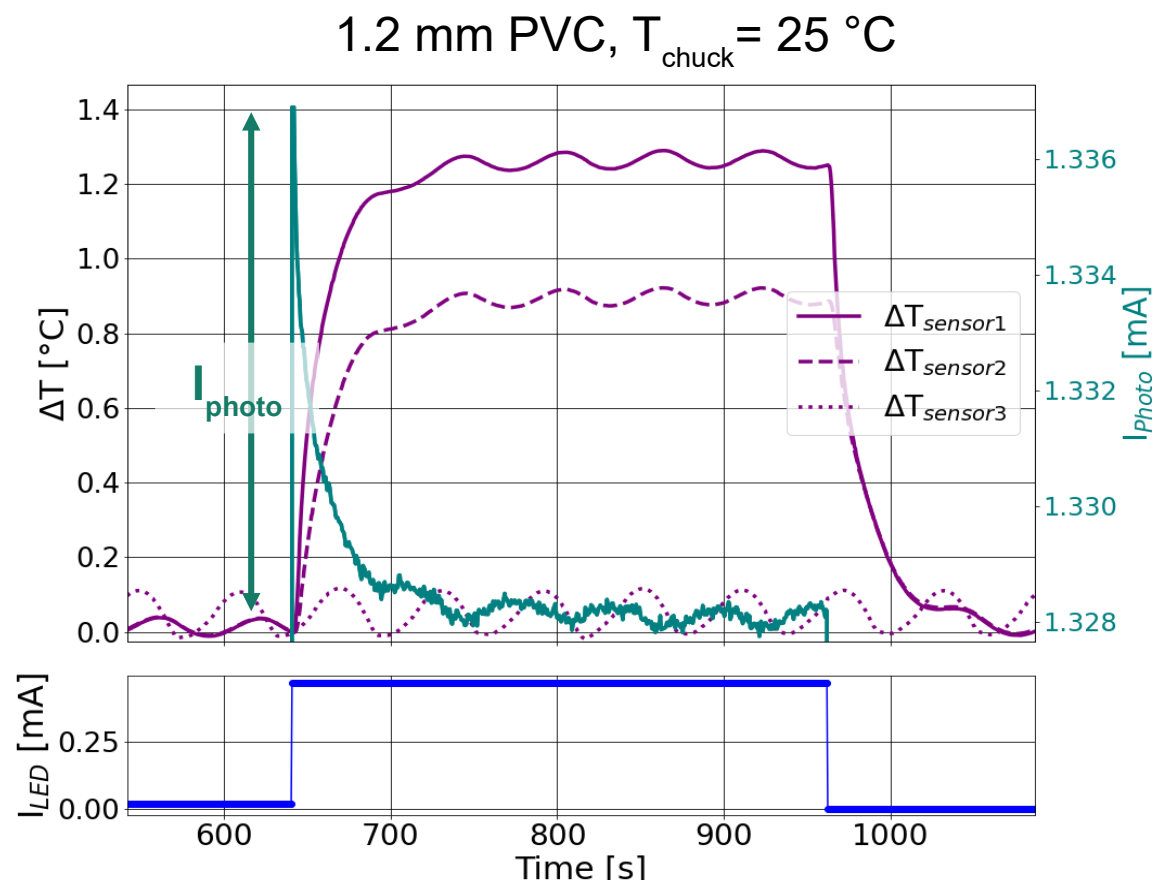
Results for degraded thermal contact (1.2 mm PVC)

- $\Delta T_{SiPM} \sim 2 \text{ K}$, for $P = 51 \text{ mW}$, reached in $\sim 60 \text{ s}$.

$$\Delta U_{bd} = 37 \text{ mV}$$

$$\Delta T_{SiPM} = \frac{\Delta I_{photo}}{S_{photo} \cdot I_{photo}}$$

- T oscillations due to feedback loop of the temperature-controlled chuck:
- Due to the increased thermal resistance \rightarrow change on the amplitude and phase of $\Delta T_{sensor1}$ and $\Delta T_{sensor2}$ relative to $\Delta T_{sensor3}$



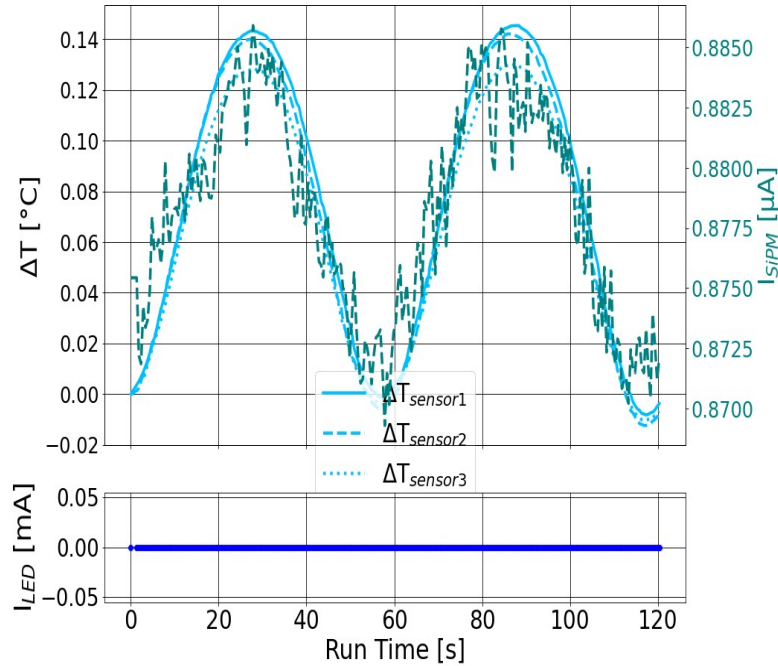
$$U_{meas} = 38 \text{ V},$$

$$I_{LED} = 0.47 \text{ mA}.$$

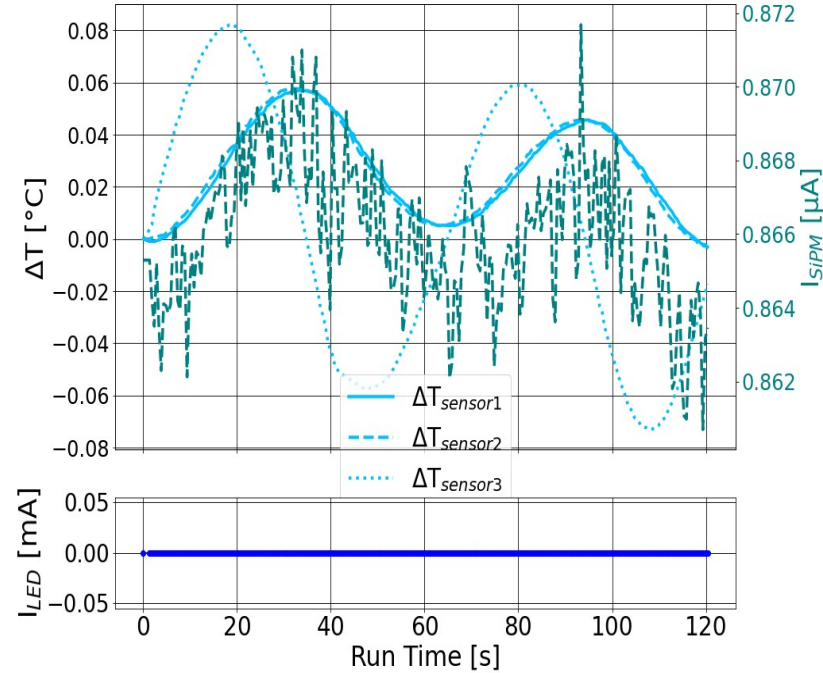
Dark current (LED = 0 mA)

- $U_{\text{bias}} = 38 \text{ V}$ and $T_{\text{chuck}} = 25 \text{ }^\circ\text{C}$:

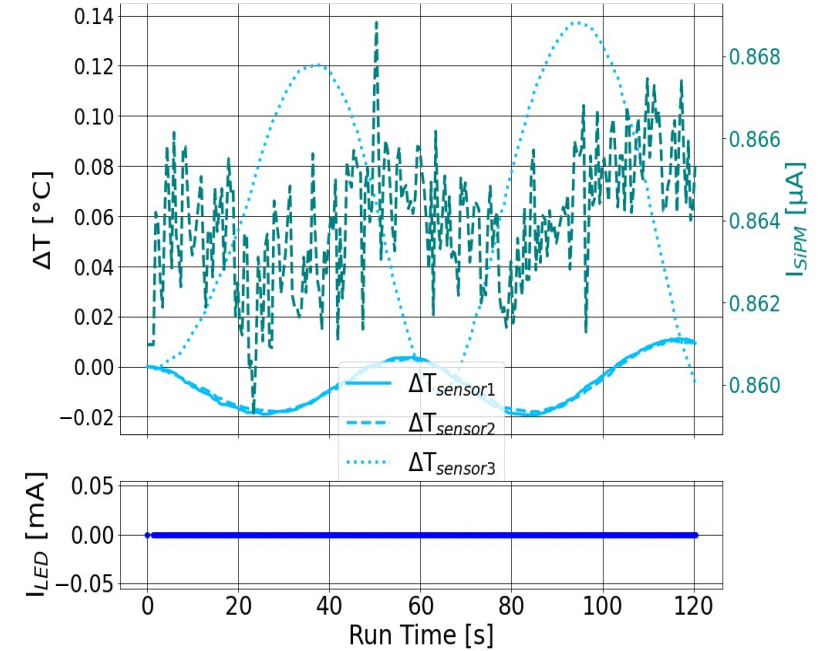
No PVC



1.2 mm PVC



3.1 mm PVC



- For I_{dark} (current depends on thermal generation, T increase and I_{dark} increase as well):

→ With good thermal contact T_{sensors} and I_{dark} are in phase with the same amplitude

→ For bad thermal contact, due to thermal diffusion there is a change on the amplitude and phase ready T_{sensor1} and T_{sensor2} (on top of the alumina) compared with the sensor on the cold chuck.